

Figure 1: Photographs of the micromanipulator with ABTECH microchip.

coating of the top chip were grounded. A manual switch was used to sequentially energize and ground the electrode arrays of the bottom chip. After an experiment, the microchips were moved apart from each other and the micro-chamber was disassembled. Then the chips were cleaned with acetone and deionized (DI) water for reuse.

Furthermore, our setup enabled us to translate the top and bottom chips relative to one another in the XY plane even while the voltage was applied, thereby providing the capability to study the combined effect of a high-gradient AC field and shear on the particle motion [3]. In principle, an electric-micro-chamber can be utilized for conducting experiments on a flowing suspension by sealing the chamber with a gasket and equipping it with the inlet and outlet tubings.

### 3. EXPERIMENTAL RESULTS

The suspensions were prepared by diluting, with DI water (pH 5.5-6.0 and conductivity  $0.55 \mu\text{S}/\text{cm}$ ), a 10% (by weight) aqueous solution of latex beads (Duke Scientific, CA, particle diameter  $3.1 \mu\text{m}$ , particle density  $1.05 \text{g}/\text{cm}^3$ ) and were introduced into the micro-chamber using a micro-syringe. The real part of the relative polarizability of the latex beads in the water within the MHz frequency range is  $\sim -0.45$  [5]. After each experiment, the chamber was dissembled and the microchips were cleaned.

As an example, the photos in Fig. 2 illustrate the behavior of the latex beads in the micro-chamber energized with applied voltage  $5\text{V}_{\text{rms}}/1\text{MHz}$ . As was the case with experiments on suspensions of negatively polarized  $87 - \mu\text{m}$  polyalphaolefin particles in low-conducting corn oil performed in a millimeter-sized device subject to  $2-5\text{kV}_{\text{rms}}$ ,  $0.1-3 \text{kHz}$  [4], the application of an AC voltage caused the beads to accumulate in the low field regions located above the grounded electrodes and to form distinct cylindrical columns [4]. These columns can be transported

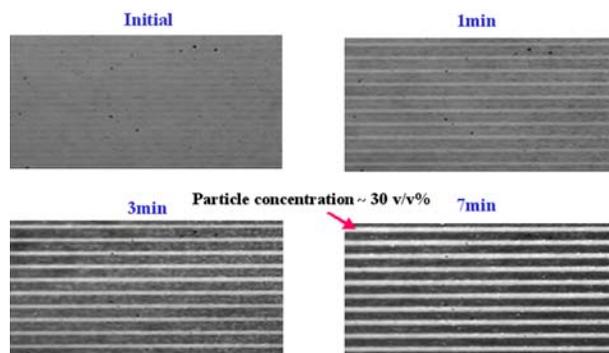


Figure 2: Distinct concentration fronts formed in low-field regions above the grounded electrodes of ABTECH microchip in 1-% suspension of latex beads;  $5\text{V}_{\text{rms}}/1\text{MHz}$ ; the gap between the top and bottom  $\sim 100$  microns.

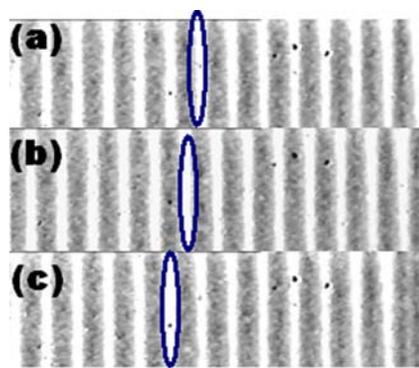


Figure 3. (a) Energizing one of the ABTECH electrode arrays and grounding the other caused the beads to form columns in the low-field regions (seen as *white*) which were then transported to another low-field regions (from a to b and to c) by sequentially energizing and grounding the ABTECH electrode arrays; 1-% suspension of latex beads;  $5\text{V}_{\text{rms}}/1\text{MHz}$ ; the gap between the top and bottom  $\sim 100$  microns. The blue circles indicate the same column.

along the chamber (Fig. 3) by sequentially energizing and grounding the ABTECH electrode arrays [3].

### 4. CONCLUSIONS

We presented a new method for assembling electro-micro-devices from several commercially available components. In contrast to currently employed techniques for studying field-driven phenomena in suspensions, the use of the proposed platform enables one to easily disassemble a micro-device after an experiment and properly clean the micro-electrodes for reuse. We demonstrated that the application of a high-gradient electric field in the MHz-frequency range caused negatively polarized particles dispersed in water to accumulate in the low field regions, forming distinct fronts. It is also possible to transport these particle structures along the chamber by sequentially

energizing and grounding microelectrodes. This fact allows one to use field-driven phenomena, which were previously observed in low-conducting oil-based suspensions in millimeter-sized devices, for the control and manipulation of aqueous suspensions at the micrometer scale.

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